



2123 #2  
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7-23-02

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Y. Granik et al.

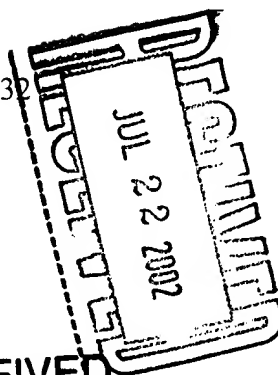
Attorney Docket No.: MEGC117332

Application No.: 09/898,431

Group Art Unit: 2123

Filed: July 2, 2001

Title: METHOD OF COMPENSATING FOR ETCH EFFECTS IN  
PHOTOLITHOGRAPHIC PROCESSING



INFORMATION DISCLOSURE STATEMENT

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July 11, 2002

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TO THE COMMISSIONER FOR PATENTS:

Applicants are aware of the information listed in the attached form that may be material to the prosecution of the above-identified patent application.

1.   X   Copies of the listed patents, publications, and other information are enclosed for the Examiner's use.
2.   X   Pursuant to 37 C.F.R. § 1.97(b), this Information Disclosure Statement is being filed within three months of the filing date of the national application (other than a CPA), within three months of the date of entry of the national stage as set forth in 37 C.F.R. § 1.491 in an international application, before the mailing date of a first Office Action on the merits, or before the mailing date of a first Office Action after the filing of an RCE.
3.   X   Pursuant to 37 C.F.R. § 1.704(d), this Information Disclosure Statement is accompanied by a statement that each item of information contained in this Information Disclosure statement was cited in a communication from a foreign patent office in a counterpart application. Such communication was received by an individual designated in 37 C.F.R. § 1.56(c) on June 17, 2002, which is not more than thirty days prior to the filing of this Information Disclosure Statement.
4.   X   The Commissioner is hereby authorized to charge any fees under 37 C.F.R. §§ 1.16, 1.17 and 1.18 which may be required during the entire pendency of the application, or credit any overpayment, to Deposit Account No. 03-1740. This

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authorization also hereby includes a request for any extensions of time of the appropriate length required upon the filing of any reply during the entire prosecution of this application.

Respectfully submitted,

CHRISTENSEN O'CONNOR  
JOHNSON KINDNESS<sup>PLLC</sup>

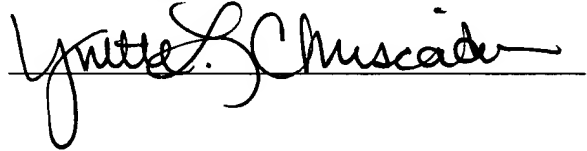


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INFORMATION CITED BY APPLICANTS THAT MAY BE MATERIAL TO THE  
PROSECUTION OF THE SUBJECT APPLICATION

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U.S. PATENT DOCUMENTS

*Examiner Initials	Cite No.	Document No.	Kind Code	Date (mm/dd/yyyy)	Name
_____	U1	5,682,323		10/28/1997	Pasch et al.
_____	U2	5,801,954		09/01/1998	Le et al.

FOREIGN PATENT DOCUMENTS

None

OTHER INFORMATION

None

Examiner

Date Considered

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\_\_\_\_\_  
\*Examiner: Initial if reference considered, whether or not citation is in conformance with M.P.E.P. § 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.RCT:yc

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